

Notice of References Cited	Application/Control No. 10/593,587		Applicant(s)/Patent Under Reexamination ALVAREZ AREVALO ET AL.	
	Examiner Andrew C. Lee		Art Unit 2419	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2003/0233666	12-2003	Onomatsu et al.	725/134
*	B	US-5,874,997	02-1999	Haigh, Stephen G	375/240.25
*	C	US-5,430,485	07-1995	Lankford et al.	348/423.1
*	D	US-2002/0100052	07-2002	Daniels, John J.	725/87
*	E	US-2004/0141731	07-2004	Ishioka et al.	386/111
*	F	US-6,101,221	08-2000	Varanasi et al.	375/240
*	G	US-7,471,874	12-2008	Kanemaru et al.	386/68
*	H	US-2002/0136205	09-2002	Sasaki, Takahiro	370/352
*	I	US-6,148,135	11-2000	Suzuki, Mitsuyoshi	386/12
*	J	US-2005/0117891	06-2005	Suzuki, Nobuyuki	386/096
*	K	US-6,130,987	11-2000	Tanaka, Mitsumasa	386/96
*	L	US-6,931,071	08-2005	Haddad et al.	375/240.28
*	M	US-7,333,721	02-2008	Maehashi et al.	386/112

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	I					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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